


Active

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#L1: (83863) (inspect$6 or detect$6) near
#L2: (431) (inspect$6 or detect$6) near1
#L3: (3694) (inspect$6) and (defect$3) and
#L4: (101719) ("250"/$7.ccls.)
#L5: (65) 2 and 3
#L6: (26) 4 and 5
#L7: (20) "6107637"

```

 Saved

✶ Favorites

Tagged (0)

UDC

④ Queue

Trash

DB5	USPAT; EPO; JPO; DERWENT
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Plurals

Default operator: **OR**

☐ Holding all the terms initially

"6107637"

☐ BGS form
 ☐ IS&R form
 ☒ Image
 ☐ Text
 ☐ HTML

	U	I	Document I	Issue D	Page	Title	Current O	Current Y	Retrieval	Inventor	S	C	P	3	3	3
1	r	r	US 6797965	2004092	14	Charged particle beam apparatus with charge monitoring and	250/491.1	250/310;		Abe; Hideaki et al.	✓	r	r	r	r	r
2	r	r	US 6791096	2004091	26	Process conditions for charge monitoring and	250/492.2	250/310;		Komuro; Osamu et al.	✓	r	r	r	r	r
3	r	r	US 6791082	2004091	26	Process conditions for charge monitoring and	250/307	250/310;		Komuro; Osamu et al.	✓	r	r	r	r	r
4	r	r	US 6757056	2004062	29	Combined high speed optical beam scanner and	356/73	257/E21.5		Meeks; Steven et al.	✓	r	r	r	r	r
5	r	r	US 6753518	2004062	54	Electron beam exposure apparatus	250/201.3	250/208.1		Watanabe; Masahiko et al.	✓	r	r	r	r	r
6	r	r	US 6744057	2004060	37	Convergent charged particle beam scanner	250/491.1	250/310;		Tanaka; Maki et al.	✓	r	r	r	r	r
7	r	r	US 6717671	2004040	50	System for simultaneous exposure	356/369	250/207		Meeks; Steven et al.	✓	r	r	r	r	r
8	r	r	US 6653632	2003112	8	Scanning-type exposure apparatus	250/310	250/307;		Kazumori; Hiroaki et al.	✓	r	r	r	r	r
9	r	r	US 6597006	2003072	21	Dual beam symmetric light exposure and	250/559.1	250/559.2		McCord; Mark et al.	✓	r	r	r	r	r
10	r	r	US 6596993	2003072	6	Method of automatically cancel	250/311	250/559.2		Sicignano; Albert et al.	✓	r	r	r	r	r
11	r	r	US 6579872	2003061	51	Bezamide derivatives	514/235.5	514/235.8		Brown; Deard S	✓	r	r	r	r	r

☒ Hits ☐ Details ☒ HTML

Brake

NEM